03500.015382.

PATENT APPLICATION

OIPE JC139
OCT 2 3 2002
PATENT & TRADEMARK OFFICE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO ET AL.

Application No.: 09/866,665

Filed: May 30, 2001

For: SILICON-TYPE THIN FILM FORMATION PROCESS, SILICON TYPE THIN FILM, AND PHOTOVOLTAIC DEVICE

Examiner: Brian L. Mutschler

Group Art Unit: 1753

October 22, 2002

#7/A
W.M.
10/30/02

RECEIVED
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TC 1700

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT AND PETITION FOR EXTENSION OF TIME

Sir:

Applicants petition to extend the time for response to the Office Action dated May 9, 2002 to November 9, 2002. A check in the amount of $920.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, and credit any overpayment, to Deposit Account 06-1205.

In response to the Office Action dated May 9, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please replace the Abstract of the Disclosure with the substitute Abstract of the Disclosure as follows:

10/24/2002 SSESHE1 00000074 09866665
01 FC:1253 920.00 OP